

Index

A

Absorbance 419
Absorber 230
Absorption 184
 coefficient 202
 edge 228, 231
 index 140
 spectroscopy 135
Accelerating voltage 146
Accidental channeling 689
Accuracy of Electron Probe
 Microanalysis 185
ADAM 244
Adsorbates 18, 225, 247, 442
Adsorption 736
 geometry 451
 isotherm 738
 site 451
AED 240
AEM 121, 136, 161
AES 310, 604
AES analysis 321
Air pollution 357
Alloy compositions 385
Amorphous materials 198, 211
Analytical
 electron microscopy 121,
 136, 161
 signals 137
 spectroscopies 144
 total 186, 187
Analyzing crystals 340
Angle-integrated spectra 303
Angular Distribution Auger
 Microscopy 244
Anharmonic vibrations 235
Annular Dark-Field Imaging 167
Antiferromagnetism 249
Antiphase domains 255

Aqueous solution 627
Archaeology 357
Art 357
Artifacts in CL 158
Atmospheric science 357
Atomic arrangements 198
Atomic Force Microscope 703
Atomic level excitation 137
Atomic Number Effect 183
Atomic plane 200
Atomic steps 272
Attenuated Total Reflection 423
Auger 144
 electron diffraction 240
 electron emission 231, 313
 electron spectroscopy 310,
 604
 electron yield 231
 electrons 311, 331
 spectrometer 321
 spectrum 319
Average
 particle-size estimations 648
 roughness 698

B

Backscattered electrons 72, 187,
 331
Backscattering 230
Band shape analysis 421
Band structure 374
Beam charging 366
Beam heating 366
Beam pulsing 365
Beam-induced conductivity 82
Beer-Lambert Law 420
Bidirectional scattering
 distribution function 716
Binding energy 138

Biology 357
Birefringence 61
Blocking 502
Blocking dips 507
Bond lengths 18, 227
Bragg's Law 201, 339, 649
Bragg-Brentano geometry 203
Bravais nets(2D) 253
Bremsstrahlung 177, 358, 360,
 367
Bright-Field Imaging 109, 167
Broadening parameter 386
BSDF 716
Bulk analysis 358, 363
Bulk conductors 601
Bulk plasmons 327
Buried interfaces 230

C

Carbon monoxide 740
Carrier types 386
Catalysts 224
Cathodoluminescence 82, 149
 analysis systems 153
 depth-resolved analysis of
 subsurface metal-semicon-
 ductor interfaces 157
 emission 151
 microscopy and spectroscopy
 149, 150, 155
CBED 161
CdMnSe 393
CdMnTe 393
CdZnTe 393
CEELS 326
CER 390
Channeling 365, 480, 502, 689
Characteristic X rays 28, 176,
 357, 359

- Characterization of optical properties of wide band-gap materials 157
- Charge-coupled device 432
- Chemical
 - bonding 136, 141, 358
 - composition 385
 - mapping 556
 - shift interactions 463
 - shifts 235
 - state determinations 143, 287, 295, 325, 342
- Chemometric techniques 422
- Cluster growth 261
- CMA 315
- Collective excitations 140
- Compositional images 162, 169, 187
- Computers 126
- Confocal microscopy 702
- Constructive interference 255
- Contactless electroreflectance 390
- Contamination 362
- Continuum 177
- Convergent beam electron diffraction 161
- Coordination numbers 18, 144, 218, 227, 460
- Core-level transitions REELS 326
- Core levels 228
- Corrosion and oxidation 357, 362
- Coulombic interaction 136
- Critical excitation energy 176
- Cross sections 144, 359, 494
- Cryosorption pumping 601
- Crystal growth at elevated temperatures 398
- Crystal structure (2D) 252
- Crystalline phases 198, 460
- CTEM 121
- Curve fitting 233
- Cylindrical mirror analyzer 315
- Czerny-Turner 432

- D**
- Damaged layer 481
- DCD 205
- de Broglie 265
- Dead time 182
- Debye-Waller factor 220, 234, 261
- Deconvolution algorithms 185
- Defects 271, 437
- Density of states 143

- Deposited layers 362
- Depth
 - profiling 364, 503, 537, 564, 698
 - resolution 498, 688, 700
 - resolved studies of defects in ion-implanted samples and of interface states in heterojunctions 150
- Detection limits in the ppm to sub-ppb range 532
- Detectors 417
- Determination of composition and thickness 343
- Deuterium tracer 500
- Device parameters 382
- Diamond 157
 - anvil cells 423
- Diamond-like carbon 496
- Diblock copolymers 668
- Dielectrics 140, 409
- Differential Reflectivity 391
- Diffraction 54, 180, 252
 - contrast 110
 - pattern 264
- Diffusion 199, 209, 261
- Digital compositional maps 190
- Direct multielemental analysis of conducting solids 622
- Direct-gap materials 152
- Dislocation contrast 155
 - densities 156
- Disorder 234
- Dispersed samples 230
- Domain boundary motion 261
- Dopants at trace levels 533
- Dot mapping 131, 187
- Double-crystal diffractometer 205
- Duoplasmatron 568
- Dynamic SIMS 40, 41
- Dynamical scattering 276
- Dynamical X-Ray Diffraction 203

- E**
- EBER 390
- EDS 103, 120, 144, 161
 - FWHM 127
- EELFS 231
- EELS 103, 135, 161
- Elastic peak 327
 - recoil detection 488
 - Recoil Spectrometry 37, 488
- scattering 137
- Electric 385
- Electric quadrupole interactions 463
- Electrically active defects 155
- Electrochemical systems 224, 231
- Electrodes 599
- Electromodulation 388
- Electron 147
- Electron beam 310
- Electron binding energy 215
- Electron Energy-Loss Spectroscopy 103, 135, 161, 231
- Electron-gas SNMS 575
- Electron impact ionization 573
- Electron irradiation (displacement) damage 146
- Electron probe microanalyzer 121
- Electron probe X-ray microanalysis 175
- Electron range 130
- Electron-stimulated desorption 568
- Electron Transport 314
- Electron yield 216
- Electron-beam electroreflectance 390
- Electronic structure 136, 141
- Electrostatic spectrometers 447
- Elemental
 - analysis of materials 136, 338
 - coverage 606
 - Depth Profiling 341
 - impurity survey 617
 - line scans 131
 - surveys 45, 607
- Ellipticity 726
- Emission 423
- Emission spectroscopy 598, 606
- Empirical parameters method 342
- Empty states 135
- Emulsion response curve 605
- Energy levels 231
- Energy resolution 127
- Energy straggling 683
- Energy-dispersive spectrometry 103, 120, 161, 179, 358
- Energy-loss function 140
- Environmental 366
- Environmental SEM 83
- Epitaxy 198, 246
- EPMA 121, 175
- ERD 488
- Error distribution histograms 185

ERS 37, 488
ES 598, 606
Ewald sphere 257, 272
EXAFS 214, 224
Excitation Spectroscopy 379
Exciton 375
EXELFS 143
Extended Energy-Loss Fine
 Structure 143
Extended X-Ray Absorption Fine
 Structure 214
External-beam PIXE 365
Extinction angle 61
Extrinsic luminescence 152

F

$f(rz)$ 131, 185
Failure analysis 586
Fermi level 140
Fermi level pinning 328, 398
Ferromagnetic 249
Fiber texture 202
Field-emission electron gun 164
Fields 385
Film crystallinity 439
 density 484
 growth 273
 on substrates 187
Fingerprinting 435
FK oscillations 392
Fluid Inclusions 439
Fluorescence 231, 375, 373, 434
Fluorescence effect 184
 yield 231, 313
 X rays 18
Forensic science 357
Forward recoil spectrometry 488
Fourier transforms 220, 232, 233
Fourier transform Raman
 spectroscopy 432
Fragmentation 550
Franz-Keldysh oscillations 392
Free electron model 140
Free induction decay 462
Fresnel reflection coefficients 404
FRS 488
Functional groups 443
Fundamental parameters method
 343

G

GaAlAs 393
GaAlInAs 393
GaAlInPAs 393
GaAlP 393
GaAsSb 393

GaAs 376, 397
GaInSb 393
Gaussian and the peak 121
GDMS 598, 606, 609
 full elemental coverage 612
Gels 438
Generation (or excitation)
 volume 151
Geological 366
Geometric effects 187
Geometric structure 227
Geoscience 357
GeSi 393
GIXD 205
Glasses 438
Glow-Discharge Mass
 Spectrometry 46, 598, 606,
 609
Glow-discharge plasma 610
GPMBE 386
Grain size 82, 198, 261
Grating spectrometer 639
 γ -ray spectroscopy 673
Grazing geometry 27
Grazing incidence X-ray
 diffraction 205
Growth modes 240, 246
Gyromagnetic ratio 461

H

Harmonic vibrations 235
Heavy Ion Scattering 497
Heavy metals 27
He-H scattering 489
Helium 139, 358
Heterojunction bipolar
 transistors 386
Heterostructures 409
HFS 488
HgCdTe 393
HgMnTe 393
high-pressure chamber 231
high-resolution
 depth profile 578
 electron energy loss spectroscopy 442
 electron microscopy 109
 transmission electro microscopy 112
Holography 248
HPGe 125
HREELS 442
Hydrides 139, 140
Hydrogen 139, 142, 144, 740
 analysis 488
 depth profiles 680
 forward scattering 488

profiling 37

I

ICPMS 47, 606
ICP-OES 633
ICP-optical 606
Image analysis 81
Impurities 361
InAsP 393
InAsSb 393
Inclusions 187
Index of refraction 405
Indirect-gap materials 152
Inductively coupled plasma mass
 spectrometry 47
Inductively Coupled Plasma-
 Optical Emission
 Spectroscopy 633
Inelastic mean free path 315
Inelastic scattering 136, 137
Infrared 417, 421
Infrared spectroscopy 416, 417
InGaAs 393
InGaAsP 393
Inner shell levels 141
InP 397
In-situ studies 386, 651, 654
Instrumentation 339
Insulating samples 79
Integrated peak intensity 422
Interaction volume 177
Interatomic distances 218
Interband transitions 326
Interelement 183
Interface Optical Effects 425
Interface structures 240
Internuclear bond distances 460
Interphase plasmon 330
Intramolecular Bond Length 237
Intrinsic luminescence 152
Ions 502
 beams 535
 implantation 386
 source 568
 yield 216
Ionization cross section 129
Ionization energy 151
Ion-sensitive emulsion detector
 600, 605
Ion-sensitive plate 600, 601
Isotope ratios 533
Isotopic tracer experiments 680

J

Joint density of states 143

K

K edges 231
K factor 132
K shell 139, 312
Kanaya-Okayama electron range 177
Kerr component 726
Kerr microscopy 730
Kinematic Diffraction 267
Kinematic factor 477
KLL Auger transition 312
Kossel pattern 82
Kramers-Kronig analysis 140

L

L shells 139
L edges 231
LAMA-III program 346
LAMMA 44
LAMMS 44
Langmuir-Blodgett films 666
Laser 561
 ablation 629, 639
 Ionization Mass Spectrometry 44
 or rapid annealing 386
Lateral resolution 324, 688, 724
Lattice rods 272
Layered film materials 187
LEED 20, 265
Light element detection 137, 182
Light microscope 7
Light Polarization 403
LIMA 44
Limiting count rate 182
Limits of detection 182
LIMS 44
Line widths 231, 385
Linear diode array 432
Liquid-metal ion guns 566
Local
 coordination 18
 order 227
 potential 81
 symmetry 460
Longitudinal geometry 727
Lorentz microscopy 106
Loss tail analysis 319
Low-Energy Electron Diffraction 20, 265
Low-energy ion sputtering 364, 575
Low-pressure RF plasma 575
LVV transition 313

M

M shells 139, 313
Magic-angle spinning 468
Magnetic
 dipole moment 35
 dipole-dipole interactions 463
 materials 651
 sector spectrometer 139
 Thin Films 657
 sector spectrometers 552
Mapping 380, 565
Mass contrast 110
Mass resolution 604
Mass scan 537
Mass spectrometer 40
Material microstructures 402
Matrix Corrections 183
Matrix effects 183, 561, 565
Matthaus-Herzog 600
MBE 265, 386
Mean free path for inelastic scattering 146
Mechanical profilers 699
Medicine 357
Medium-energy ion scattering 502
Memory effects 601
Metal area 740
Metal dispersion 740
Metal hydrides 328
Metalloenzymes 224
Metallurgy 357
Methods for Surface and Thin-Film Characterization 321
Metrology 81
Microbeams 365, 680
Microdensitometer 605
Microdiffraction 107
Microscopy 424
Miller indices 200, 253
Minimum detection limit 120
MOCVD 386
Model compounds 230, 235
Modulation spectroscopy 30, 385
MOKE 724
Molecular 236
 adsorbates 18, 236
 area 739
 beam epitaxy 265
 orbital 236
 orientation 228
Monolayers 738
Monolayer volume 739
Monte Carlo simulations 177, 507

Moseley law 339
MPI 562
Multichannel analyzer 123, 179
Multielement analysis 27
Multielement standards 186
Multi-element surveys 606
Multilayers 198, 211
Multiphoton 562
Multiphoton ionization 560, 562
Multiple reflection effects 425
Multiple scattering 146, 234, 262
Multiply charged species 605

N

N shells 139
NAA 671
Nearest neighbors 18, 136, 144, 227, 233,
Near-surface temperatures 386
Neutron Activation Analysis 671
Neutron flux 672
Neutron reflectivity 50
Neutron sources 648, 653
NEXAFS 235
Nitrogen 56
NMR 35
Nonconductors 129, 311, 602, 689
Nonresonant multiphoton ionization 587
Nonresonant profiling 684
Nonselective photoionization 562
Normalization 187
NRA 680
Nuclear reaction analysis 680
Nuclear reactors 651
Numerical aperture 63

O

O shells 139
Optical
 CL microscopes 154
 coatings 409
 constants 140, 401
 factor 713
 microscope 182
 Profiler 700
 scatterometry 54, 704
 spectroscopy 633
Ordering of magnetically active atoms 648
Organic polymers 587
Overlayer unit mesh 259
Overlayers 246

- Overvoltage 177
Oxidation state 18, 235
Oxides 362
Oxygen 740
- P**
- Partial electron yield 231
Particle 187
 accelerators 484
 size 740
 spectrometry 490
Particle-Induced X-Ray Emission 28, 357
Particles 187
Passive films 224
Pattern recognition techniques 587
Peak position and width 421, 422
Peak-to-background ratio 182
Peltier cooling 126
Penning ionization 610
Phase
 composition 198
 contrast 112
 formation 199
 identification 169, 206, 648
 shift 232, 229
 transitions 261, 435
Phonon modes 443
Phonon-scattered incident electrons 138
Phosphorescence 375
Photoelectric absorption 184
Photoelectron wave 228
Photoionization 562
Photoluminescence 373
Photon energy 228
Photorefectance 389
Physical adsorption 737
Piezomodulation 388
Piezoreflectance 390
Pile-up 124
PIXE 28, 357, 358, 365
 and low-energy ion sputtering 365
 and RBS 364
Plasmon 138, 140, 326
Pleochroism 61
Point group and space group determination 168
Point-to-plane 607
Point-to-plane surface technique 604
Polarization measurement 407
Polarization vector 229, 236
Polarized light microscope 61
 high-energy electron diffraction 253
Reflectivity 140, 663
Refractive index 61, 140, 661
Region of interest (ROI) 131
Reliability comparison 507
Residual stress measurements 648
Resonance (π) 236
Resonant profiling 683
RF spark 605
R factor 507
RHEED 253, 264
Root-mean-square roughness 698
Rotation 726
Rough surfaces 187
Roughness 54, 698
RUMP 497
Rutherford backscattering spectrometry 36, 476
Rutherford backscattering spectroscopy 311
Rutherford scattering 502
- S**
- s resonance 236, 237
SAD 107
SALI 42, 559
 imaging 566
Sample Rotation 707
Scanning Electron Microscope 8, 70 121, 701
Scanning force microscope 703
Scanning transmission electron microscope 161
Scanning Tunneling Microscope 703
Scattering cross section 478, 481
Schottky barrier formation 386
Schottky barrier heights 328
Scintillation counters 341
Searchlight effect 229
Secondary electron 72, 315
Secondary fluorescence 184
Secondary ion mass spectrometry 40
Secondary ion mass spectrometry 311
Secondary ion yield 706
SEELFS 328
Seemann-Bohlin geometry 204
Selected-area diffraction 107
Selective chemisorption 743
SEM 121, 701
Semiconductor 350, 357, 409, 601
- Polarized neutrons 50
Polyatomic 604
Polyethylene slug die 602
Polymer 379, 380
Polymer surfaces 454
Porto notation 433
Post-ablation ionization 588
Post-ionization 559, 573
Powders 602
PR 389
Preferred orientation 198, 208
Primary and secondary excitations 343
Probing depth 324, 724
Process- or growth-induced strains 386
Profilometers 699
Protons 358
- Q**
- Q values 681
Quadrupole spectrometers 551
Qualitative analysis 183, 338
Quantification 155, 366
Quantitative
 analysis 120, 183, 342
 compositional mapping 188
 compositional measurements 141, 338
 concentration measurements 144, 145
 depth-profiling 476
quantum wells 156, 374, 379
- R**
- Radiation damage 498
Radiofrequency 35
Raman scattering 429
Raman spectroscopy 429
Range of electron penetration 151
RBS 311, 476
Reaction cross sections 681
Reactive-ion etching 386
Reciprocal lattice 257, 267
Recoil cross section (1H) 494
Reconstructions 503
REELM 328
REELS 25, 324
Reflectance 419
Reflected electron energy-loss microscopy 25, 324, 328
Reflection 423
 absorption (RA) spectroscopy 423
 Difference Spectroscopy 391

- Sensitivity 688
 - SEXAFS/NEXAFS 18
 - short-range order 223
 - short-range single scattering 221
 - Si 271, 378
 - Si (Li) detectors 123, 126
 - Sign of elongation 61
 - SIMS 40, 41, 311, 604
 - Simulation Programs for NRA 690
 - Single scattering 232, 234
 - Single crystal surfaces 442
 - Single-Layer Films 343
 - Single-pass transmission 422
 - Single-photon ionization 560, 562
 - SMOKE 724
 - Snell's Law 404
 - SNMS 43
 - comprehensive elemental coverage 578
 - concentration depth profiles 572
 - Solid state effects 143
 - Solid state nuclear magnetic resonance 35
 - Spallation 652
 - Spallation sources 665
 - Spark Source Mass Spectrometry 598
 - Spark source mass spectrometry 45
 - Spatial resolution 153, 179
 - Spatial uniformity of stresses in mismatched heterostructures 156
 - Spectral acquisition 180
 - Spectral resolution 180
 - Spectroelectrochemistry 224
 - Spectrum Simulation 497
 - SPI 562
 - Spin-lattice relaxation time 463
 - Spin-orbit splitting 289
 - Spin-Polarized Photoelectron Diffraction 248
 - Sputtered neutral mass spectrometry 43
 - Sputtering 40, 43, 147, 363, 386
 - SREM 264
 - SSMS 45, 598, 606
 - Standardless methods 186
 - Standards 145
 - Standards or reference materials 547
 - Static 234
 - Static Secondary Ion Mass Spectrometry 41
 - STEM 121, 135, 139, 161
 - Step density 260
 - Stereo imaging 702
 - STM 703
 - Stokes scattering 430
 - Stopping cross section 480, 481
 - Straggling 499
 - Strain 198, 207, 385
 - Stress distributions in epitaxial layers 150
 - Structural information 240
 - Structural parameters 503
 - Substitutional 481
 - Substrate Temperature 397
 - Sum peak 124
 - Superconducting Oxides 655
 - Superlattices 374
 - Surface 240
 - Analysis by Laser Ionization 42, 559
 - and interfacial roughness 401
 - Areas by the BET Method 736
 - atomic structure 260
 - charging 367
 - chemical information 41
 - crystal structure 265
 - crystallography 20
 - damage 374
 - disorder 20
 - electron energy-loss fine structure 328
 - Extended X-Ray Absorption Fine Structure and Near Edge X-Ray Absorption Fine Structure 18
 - factor 713
 - layers 358, 361,
 - layers on bulk specimens 362
 - magnetic ordering 249
 - Melting 249
 - or interface electric fields associated with surface or interface states and metallization 386
 - order 260
 - order-disorder transition 249
 - orientation 265
 - plasmons 327
 - reconstruction 271
 - roughness 265, 698
 - segregation 240
 - sensitivity 291
 - states 328
 - topography 54
 - analytical technique 350
 - enhanced Raman spectroscopy 434
 - and interfaces 503
 - Survey analysis 586, 598
 - Surveys 564
 - Synchrotron radiation 18, 198, 199, 214, 230
 - Synthetic multilayers 340
- ## T
- TEAS 265
 - TEM 135, 139
 - Temperature 385
 - Thermal-energy atom scattering 265
 - Thermomodulation 388
 - Thick or bulk specimens 361, 362
 - Thin films 121, 199, 240, 357, 358, 361, 362, 402
 - Threshold energy 138
 - Tilted molecule 237
 - Time-of-Flight Mass Spectrometry 552, 563, 586
 - TOFMS 563
 - Topographical variations in carrier concentrations 386
 - Topography formation 704
 - Toroidal high-resolution ion energy analyzer 507
 - Total electron yield 231
 - Total Reflection X-Ray Fluorescence Analysis 27, 349
 - Total surface areas 737
 - Trace impurities 675
 - Trace level analysis 45
 - Transitions that lead to luminescence 152
 - Transmission 135
 - Transmission electron microscopy 10, 121
 - Transmission or scanning transmission electron microscope 135
 - Transmittance 419
 - Transverse geometry 727
 - Trap states 386
 - True secondaries 331
 - TXRF 27
- ## U
- Ultrahigh spatial resolution 147
 - Ultrahigh vacuum 18, 231
 - Ultratrace analysis 609
 - Ultraviolet laser pulse 587

- Ultraviolet photoelectron spectroscopy 23
 - Uniform ionization 572
 - Uniformity characterization of luminescent materials 149
 - Unit vectors 200
 - UPS 23
- V**
- Vacuum ultraviolet light 562
 - Valence
 - band electrons 140
 - bands 249
 - EELS 327
 - electron densities 140
 - levels 285
 - level spectra 303
 - Vapor phase decomposition 352
 - Variable-angle spectroscopic ellipsometry 31
 - VASE 31
 - VEELS 327
 - Vibrational spectra 443
 - Visual method 605
 - VPD 352
- W**
- Water analysis 357
 - Wavelength-dispersive spectrometry 179, 340, 425
 - Wavelength-dispersive X-ray spectroscopy 103
 - WDS 103, 125
 - White lines 142
 - Windowless EDS 141
 - Working distance 77
- X**
- XAFS 215
 - XANES 215
 - XAS 215
 - XPD 240
 - XPS 22, 311
 - X-ray
 - absorption and enhancement effects 18, 343
 - absorption fine structure 215
 - absorption near-edge structure 215
 - absorption spectroscopy 215
 - Data Booklet 239
 - Detection Systems 341
 - diffraction 198, 252, 265
 - fluorescence 26, 216
 - generation 121
 - generation range 130
 - maps 72
 - Microanalysis 166
 - photoabsorption 215
 - photoelectron diffraction 240
 - photoelectron spectroscopy 22, 311
 - Sources 340
 - spectrum 358
 - topography 210
 - XRD 198
 - XRF 26, 349
 - XRF analysis of multiple-layer films 344
 - XRF thin-film analysis 343
- Z**
- ZAF 132
 - ZAF method 184
 - ZnMnTe 393

ENCYCLOPEDIA OF MATERIALS CHARACTERIZATION

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